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(71) Applicant (for all designated States except US):
NANYANG POLYTECHNIC [SG/SG]; 180 Ang Mo
Kio Avenue 8, Singapore 569830 (SG).

(72) Inventor; and

(75) Inventor/Applicant (for US only): **ABU SAMAH, Zu-
ruzi Bin** [SG/SG]; Blk 117, Ang Mo Kio Ave 4 #03-447,
Singapore 560117 (SG).

(74) Agent: **ALLEN & GLEDHILL LLP**; One Marina
Boulevard #28-00, Singapore 018989 (SG).

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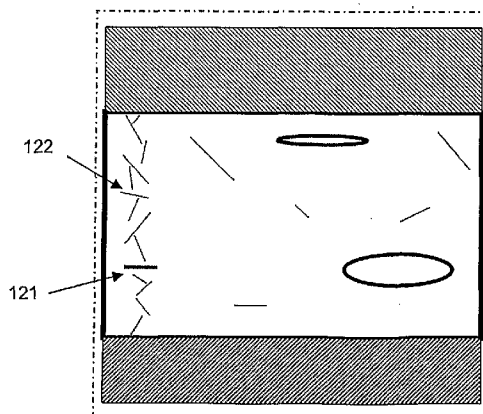


Figure 4

(57) Abstract: A method of forming a film is described. The method begins by forming a mixture including a polymer and a plurality of unordered nanomaterial. The film is dried and a plurality of pores is formed within the film. A sensitive film transducer capable of detecting changes in pressure and applied force can be made using this method.